

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Declaration Under 37 C.F.R. 1.131

Atty. Docket No. FOC1100-1

Applicant Robert Jackson	
Application Number 10/038,745	Date Filed 01/02/2002
Title Method and System for On-Site Generation and Distribution of a Process Gas	
Group Art Unit	Examiner Nguyen, Ngoc Yen M.
Confirmation Number: 2978	, Ngayon, Ngoo rom un

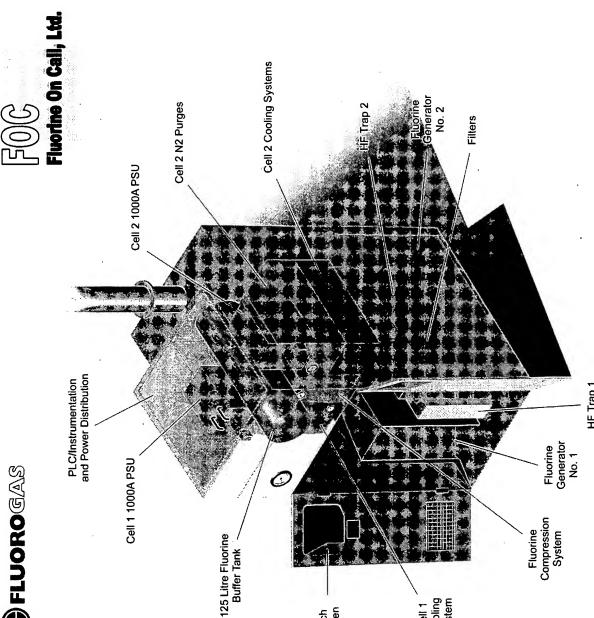
- 1. I, Robert Jackson, am the sole inventor of the invention described and claimed in the above-referenced patent application.
- 2. The invention claimed in the above-referenced patent application was conceived at least as early as November 29, 2000.
- 3. Attached hereto as Declaration Exhibit A is a copy of a presentation dated November 29, 2000. This presentation is saved as "11 29 2000 Semiconductor Fluorine Plant670" on Fluorine On Call's ("FOC") computer system and was generated by FOC at least as early as November 29, 2000. Slides 2 and 3 of the presentation show parallel HF traps coupled to fluorine generation cells and a filter downstream of the HF traps. Slide 3 further shows a low pressure buffer and compressor downstream of the HF traps. Slides 2 and 3 also illustrate various flow paths provided by manifolds. Slide 4 of the presentation describes that the HF traps are NaF traps and that switching occurs.
- On November 26, 2001, a provisional patent application was filed disclosing the invention.
- 5. Declarant acknowledges that willful false statements and the like are punishable by fine or imprisonment, or both (18 U.S.C. 1001) and may jeopardize the validity of the application or any patent issuing thereon.

I, Robert Jackson, aver that all statements made of my own knowledge are true and all statements made on information and belief are believed to be true.

Røbert Jackson April 10<sup>th</sup> 2006

### **DECLARATION EXHIBIT A**





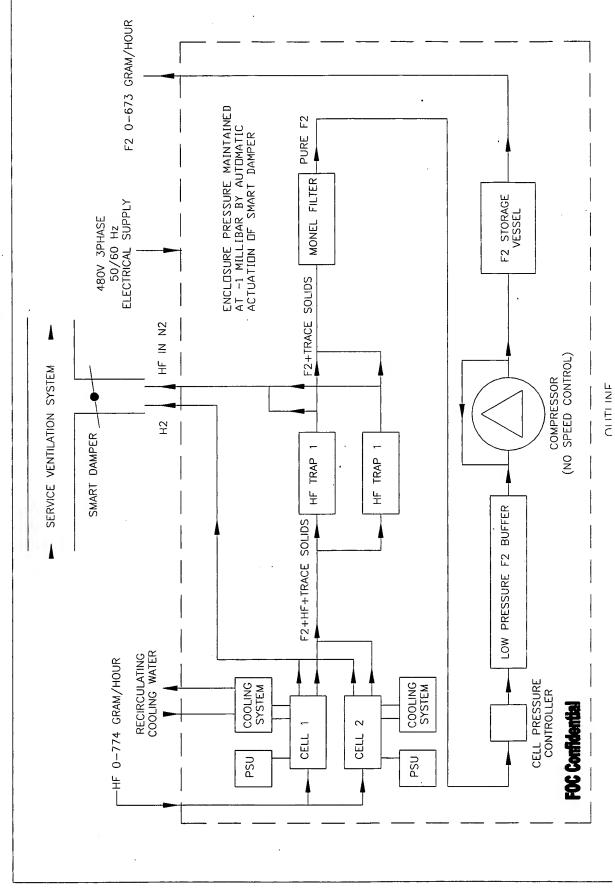
Touch Screen

Cooling System

### Semiconductor Packaged Fluorine Cell F00 Confidential

### F2 0-673 GRAM/HOUR PURE F2 Process Flow Diagram MONEL FILTER STORAGE VESSEL 480V 3PHASE 50/60 Hz ELECTRICAL SUPPLY F2 F2+TRACE SOLIDS BELLOWS COMPRESSOR SPEED CONTROLLED TO MAINTAIN CELL PRESSURE AT SET POINT HF IN N2 OUTLINE PROCESS FLOW DIAGRAM SERVICE VENTILATION SYSTEM OPTION A H2 SMART DAMPER HF TRAP HF TRAP F2+HF+TRACE SOLIDS ENCLOSURE PRESSURE MAINTAINED AT -1 MILLIBAR BY AUTOMATIC ACTUATION OF SMART DAMPER RECIRCULATING COOLING WATER HF 0-774 GRAM/HOUR COOLING COOLING SYSTEM CELL 2 CELL PSU PSU

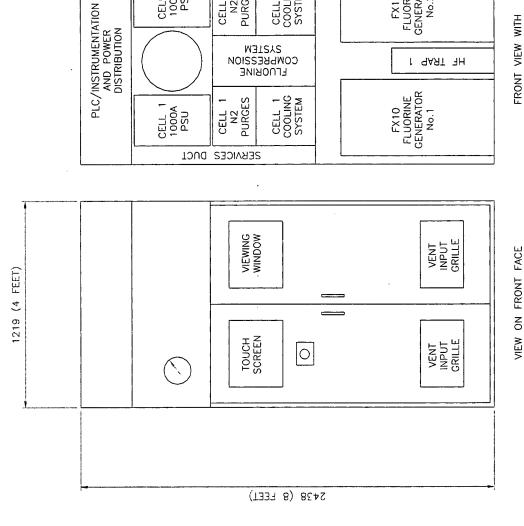
### Process Flow Diagram



- Duty and stand-by design
- PLC controlled automated switch-over
- PLC controlled automated regeneration capability
- Proven high efficiency absorption path design
- PLC monitoring of upcoming change-out and service requirements
- Low metallic impurities, Monel construction, Stainless steel jacketed
- Simple MTTR design



## Conceptual Component Layout (1)



SERVICES DUCT

CELL 2 N2 PURGES

CELL 2 COOLING SYSTEM

CELL 2 1000A PSU

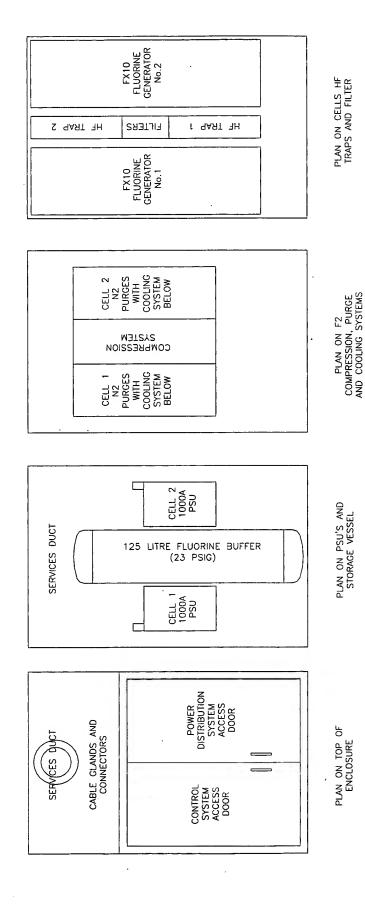
FRONT VIEW WITH DOORS REMOVED

FX10 FLUORINE GENERATOR No.2

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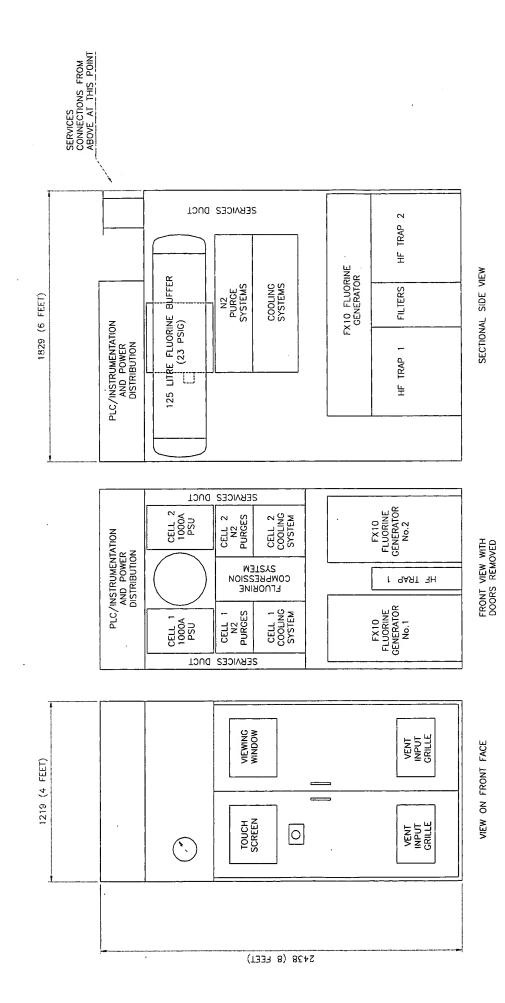
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# Conceptual Component Layout (2)



### יסווכעוויס ושמילטווטו -ayout (3)

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